

FIG. 1 is a schematic diagram of an optical system 100. The system includes a light source 102, a beam splitter 106, a lens 108, a detector 112, and a series of waveguides 104a, 104n, 105. The waveguides are connected to the beam splitter 106 and the detector 112. The system is configured to measure the phase shift of light passing through the waveguides.

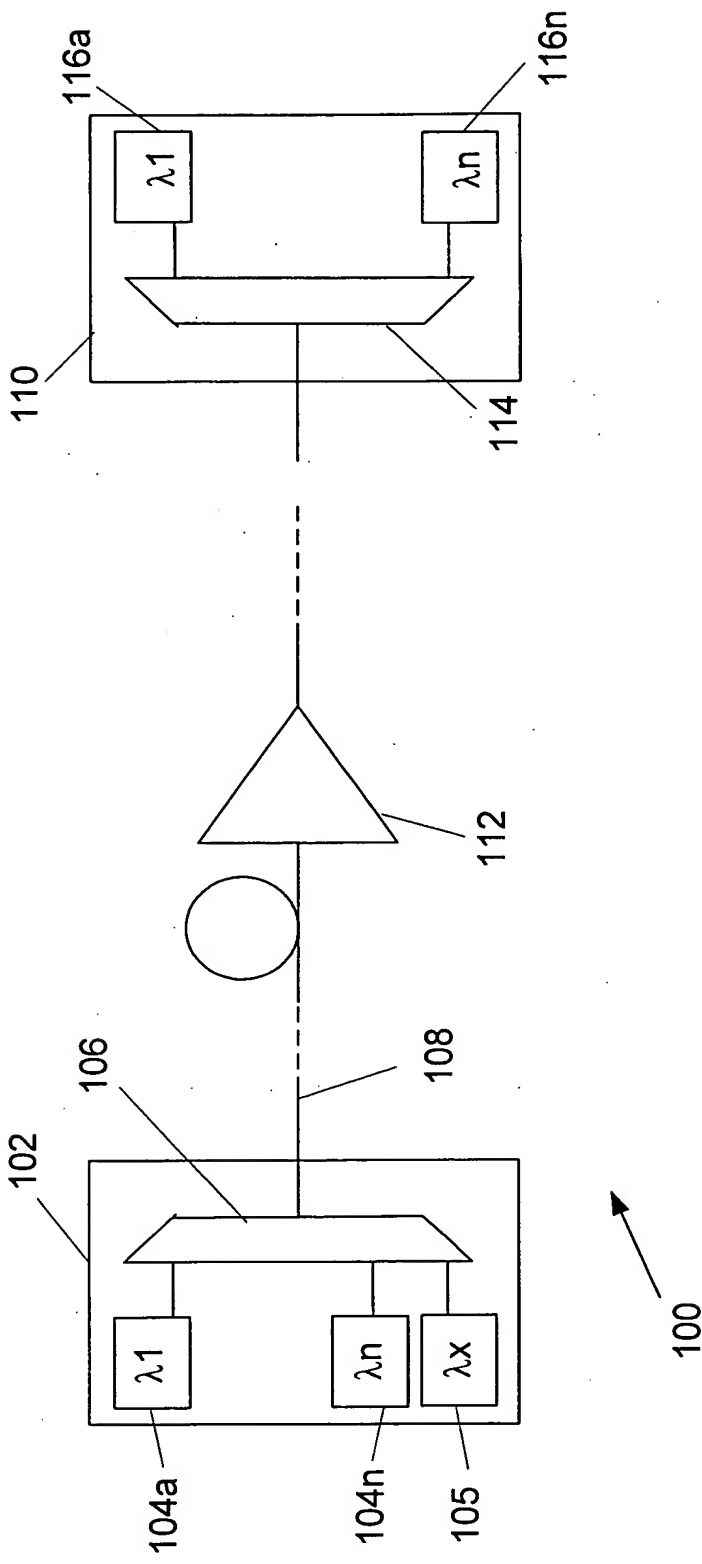
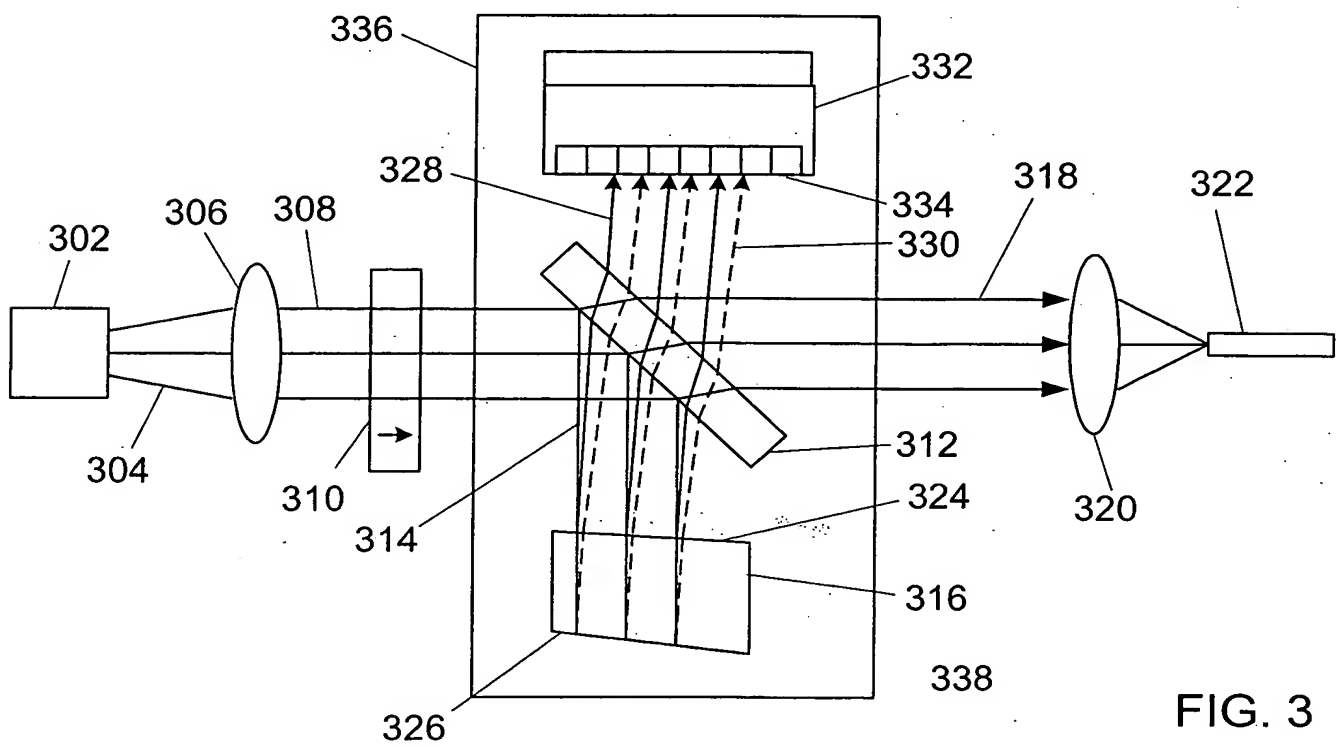
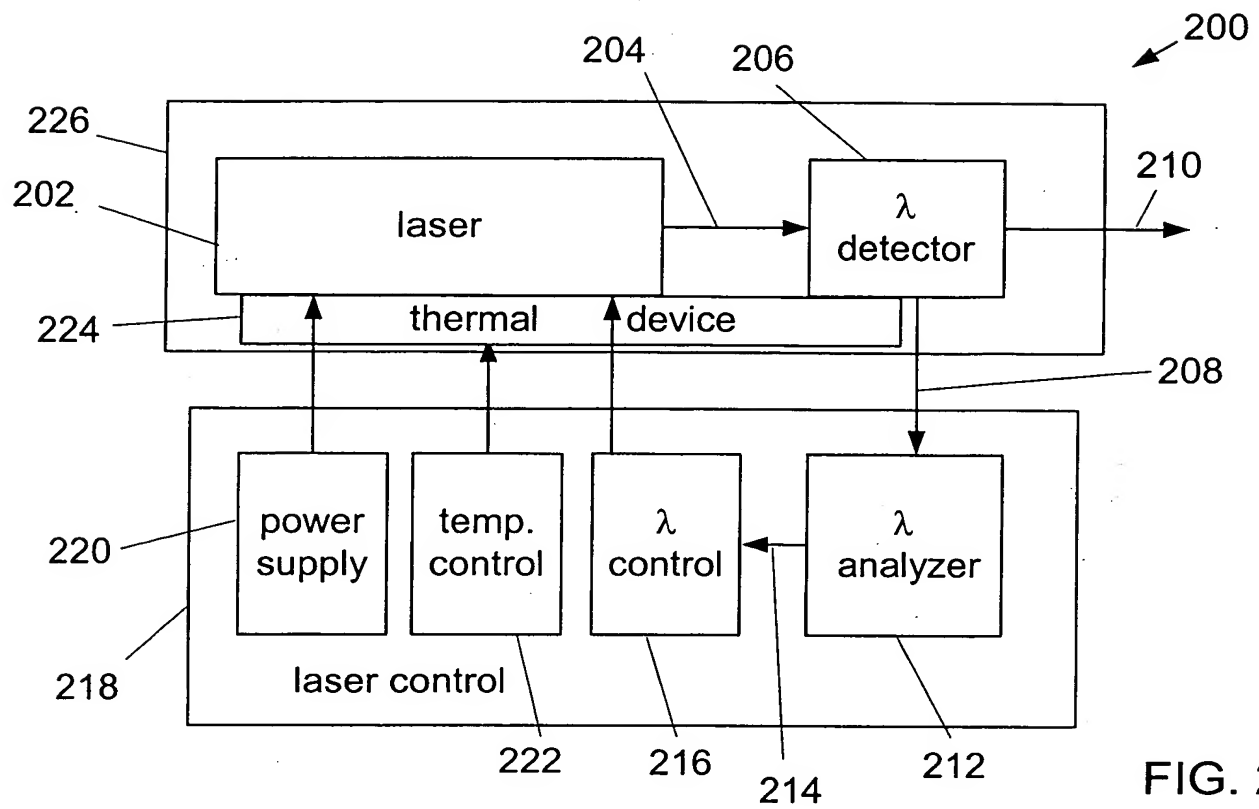


FIG. 1



1. The present invention relates to a method of measuring the thickness of a thin film.

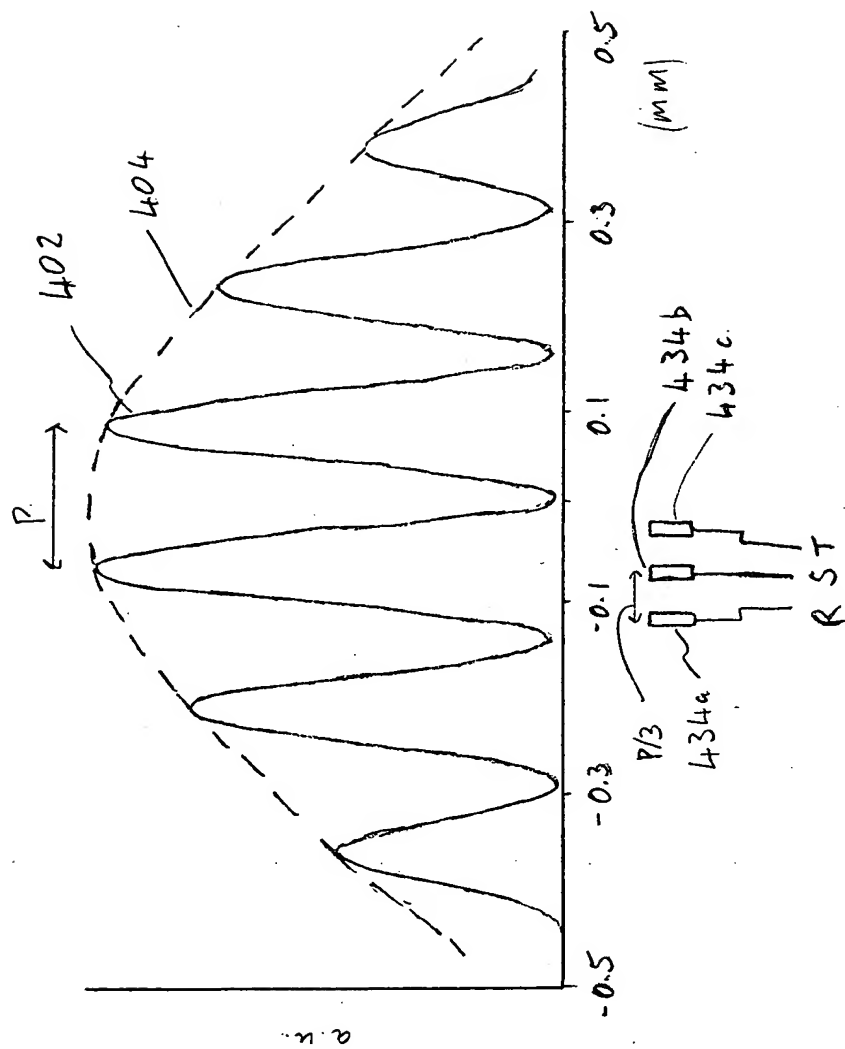


FIG. 4

1. The first part of the figure shows a series of peaks labeled 402 and 502. The x-axis is labeled 'position [mm]' and ranges from -0.5 to 0.5. The y-axis is labeled 'a.u.' and ranges from 0 to 12. The peaks are shown as solid and dashed lines.

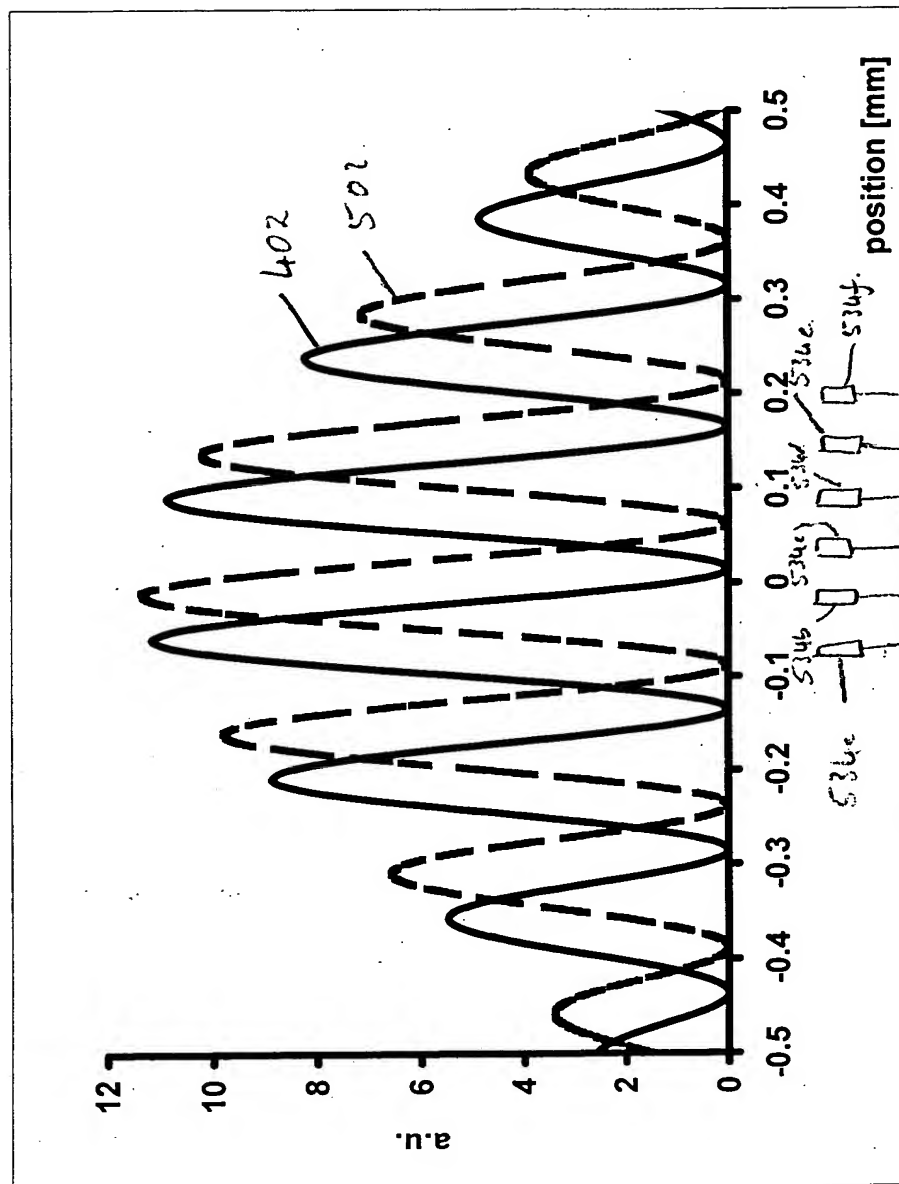


FIG. 5.

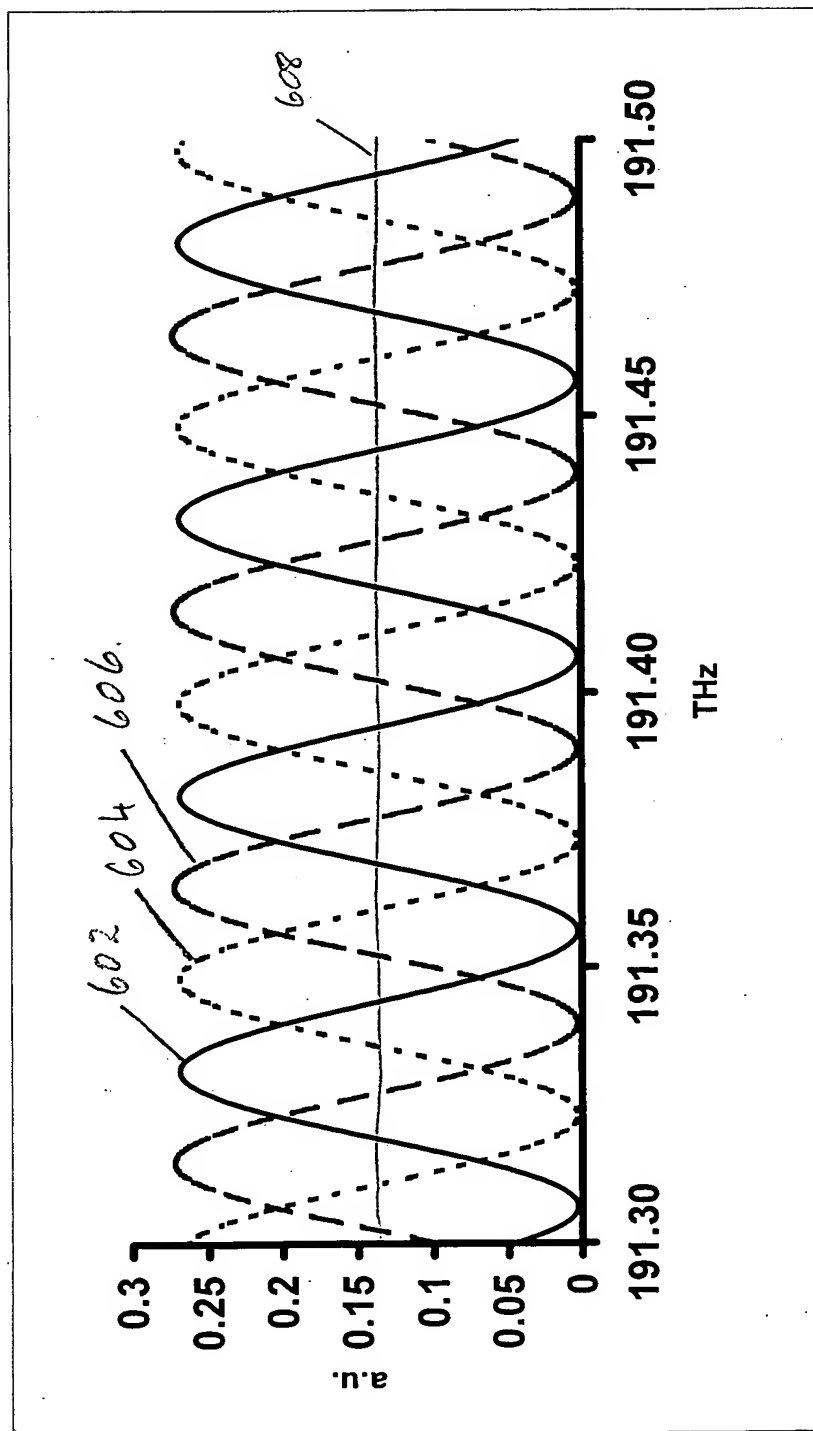


FIG. 6

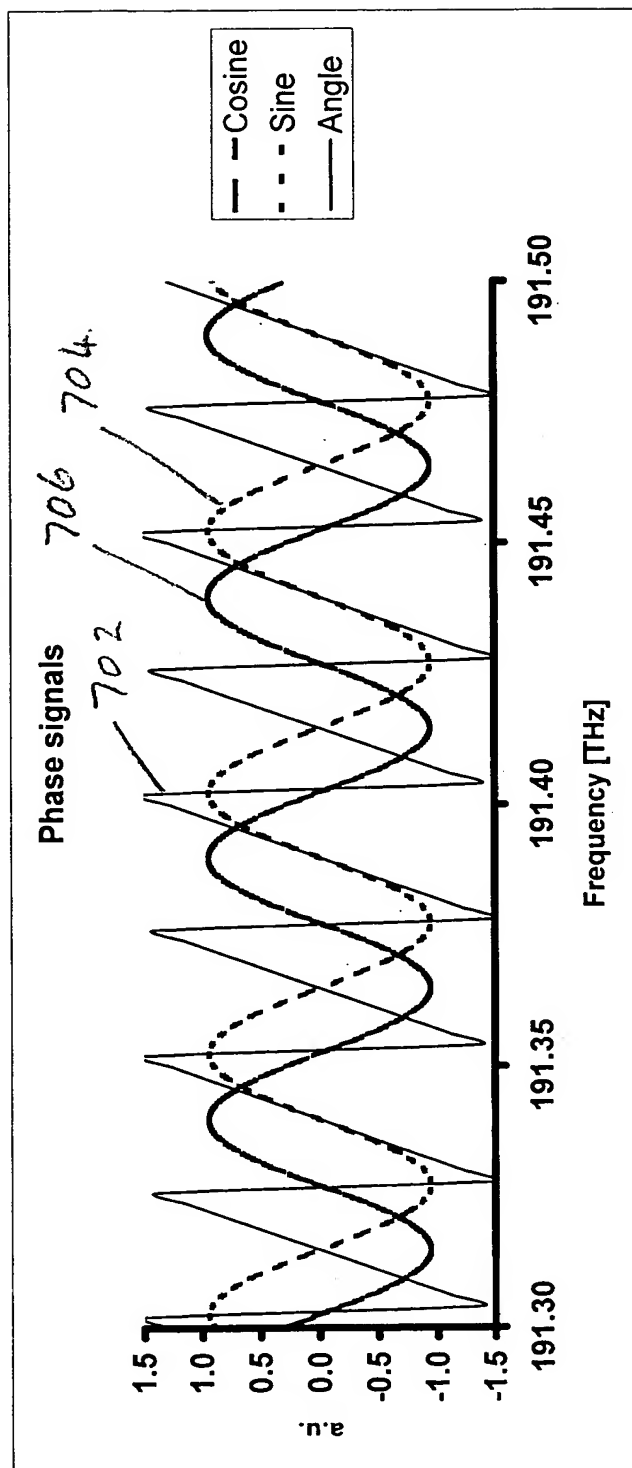


Fig. 7

FIG. 8 is a graph showing the magnitude and phase of the feedback signals as a function of frequency. The x-axis represents frequency in THz, ranging from 191.37 to 191.43. The y-axis represents the magnitude in arbitrary units (a.u.), ranging from -1.5 to 1.5. The solid line represents the magnitude of the feedback signals, and the dashed line represents the phase of the feedback signals. The magnitude curve shows a resonance peak around 191.41 THz, while the phase curve shows a corresponding phase shift.

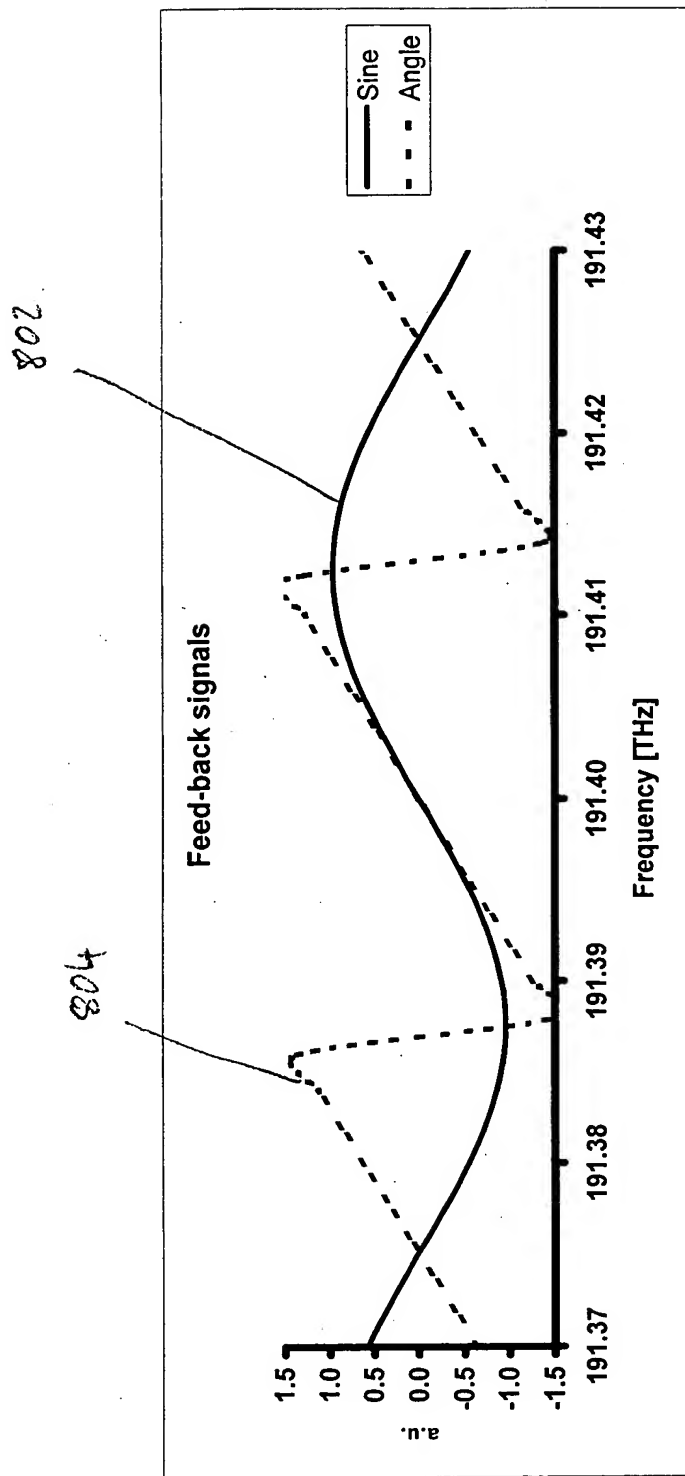


FIG. 8

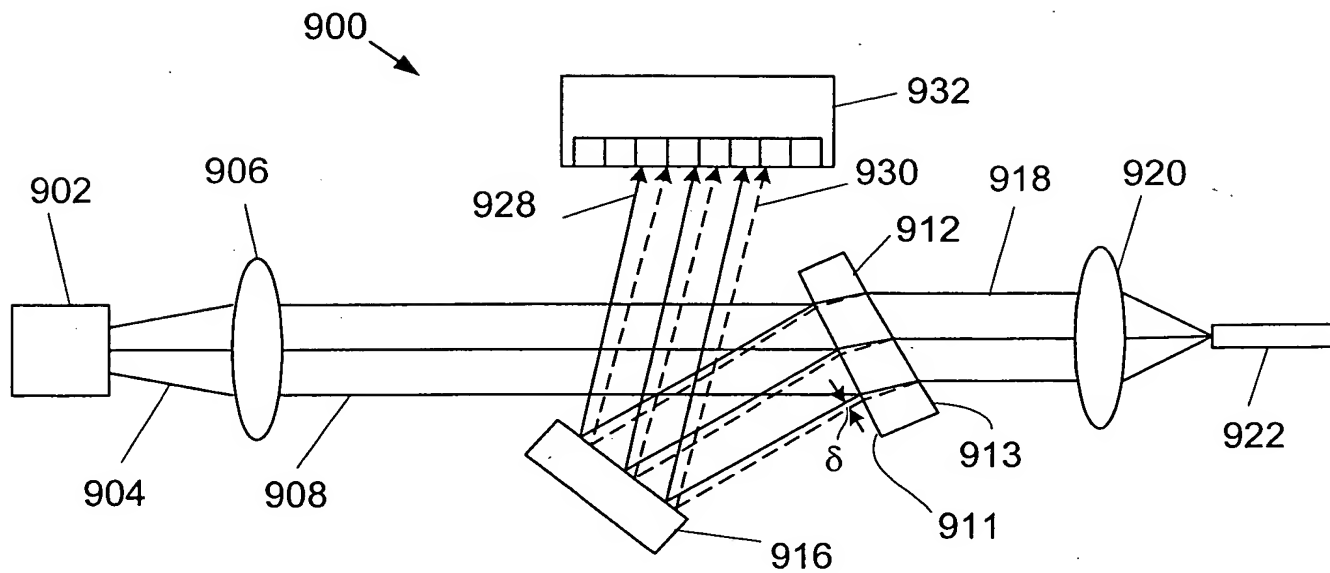


FIG. 9

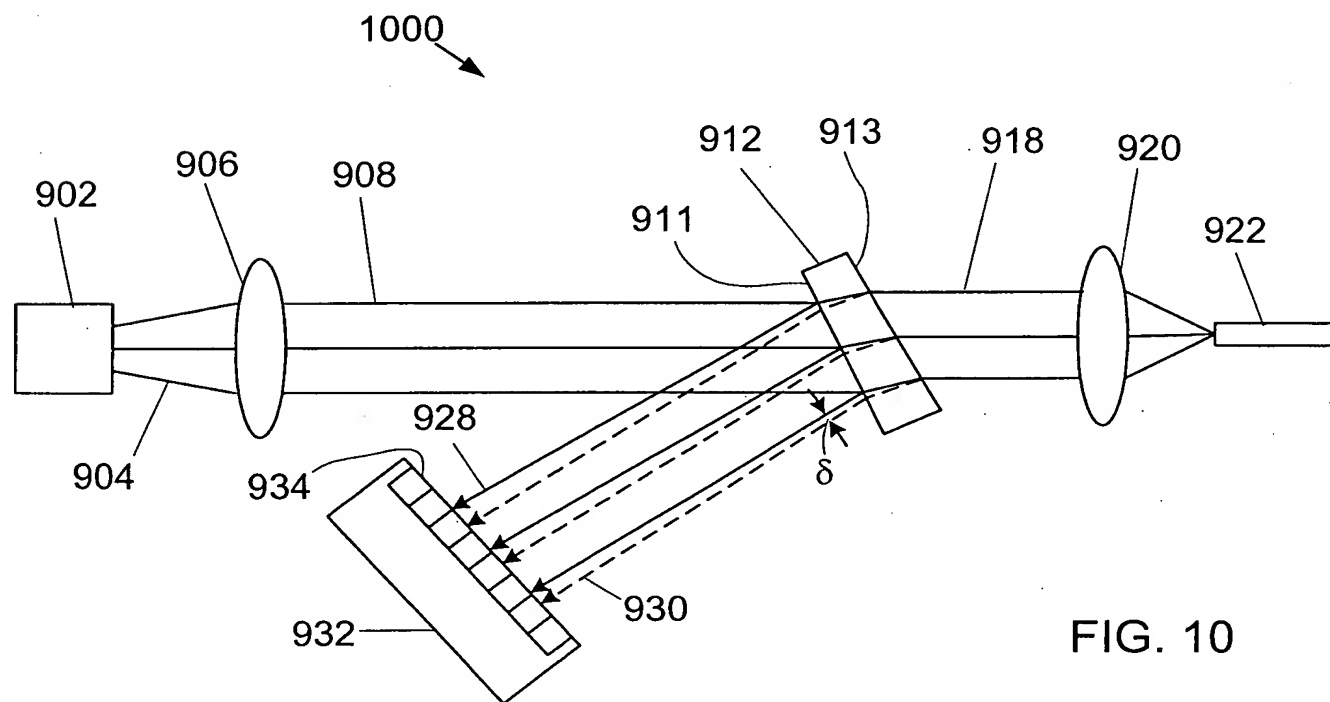


FIG. 10



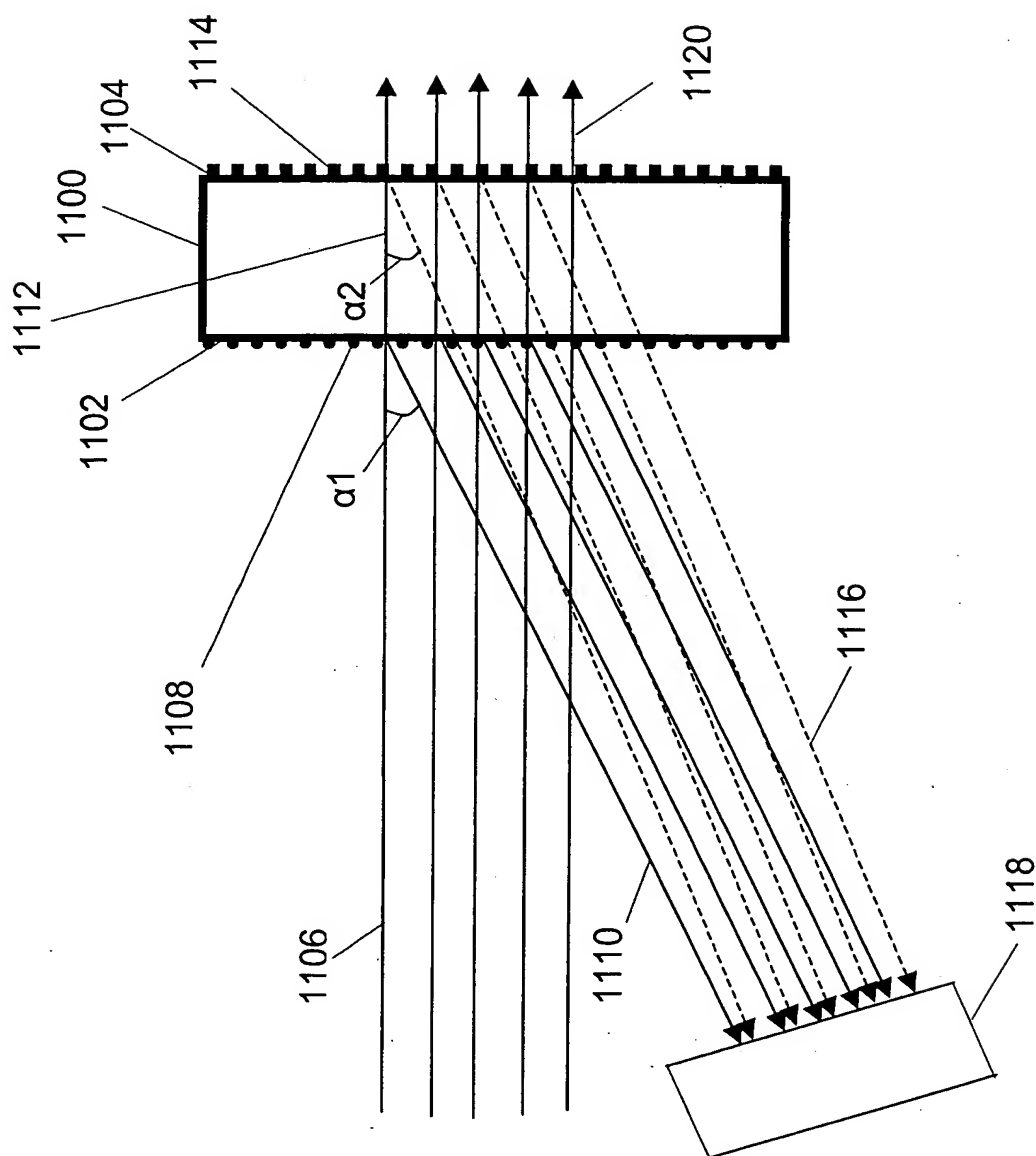


FIG. 11

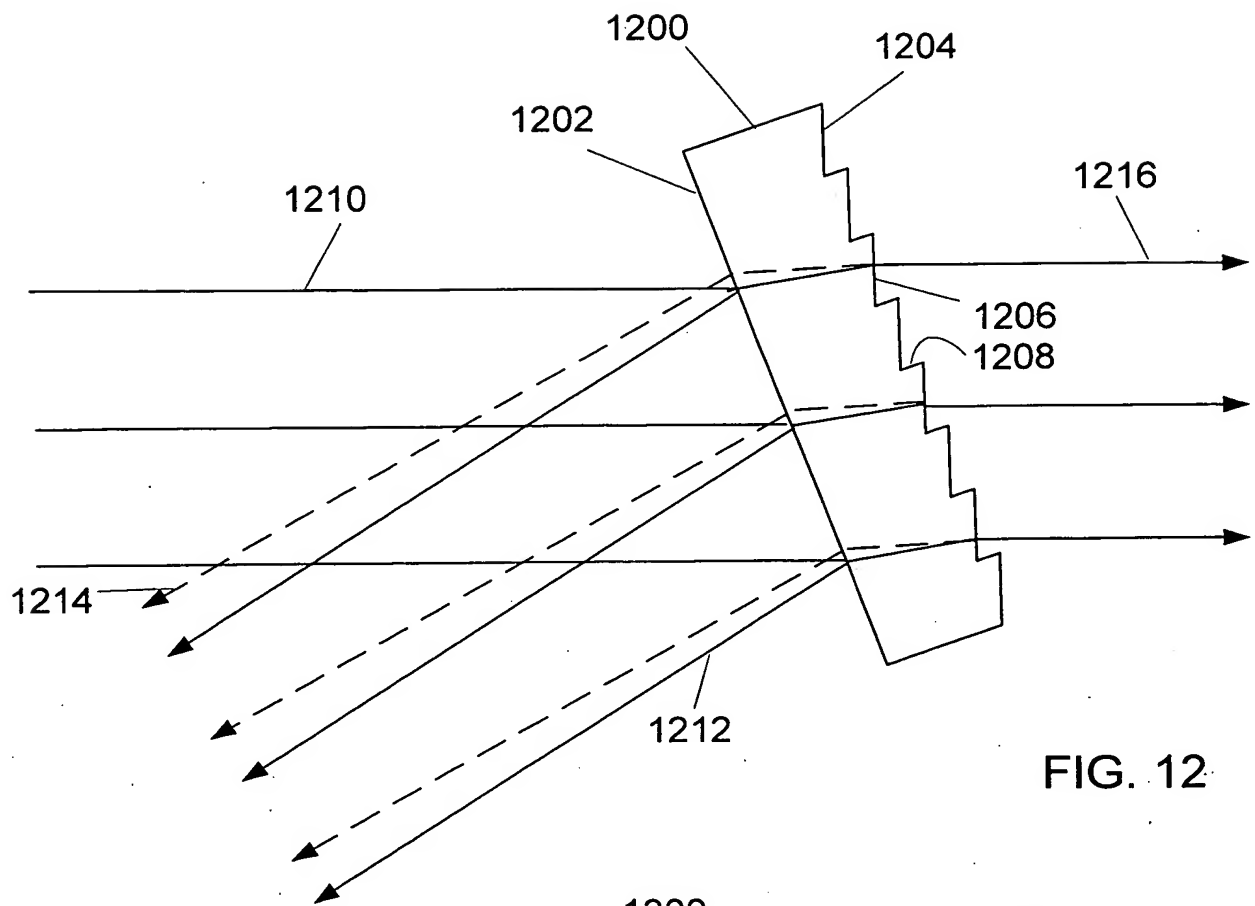


FIG. 12

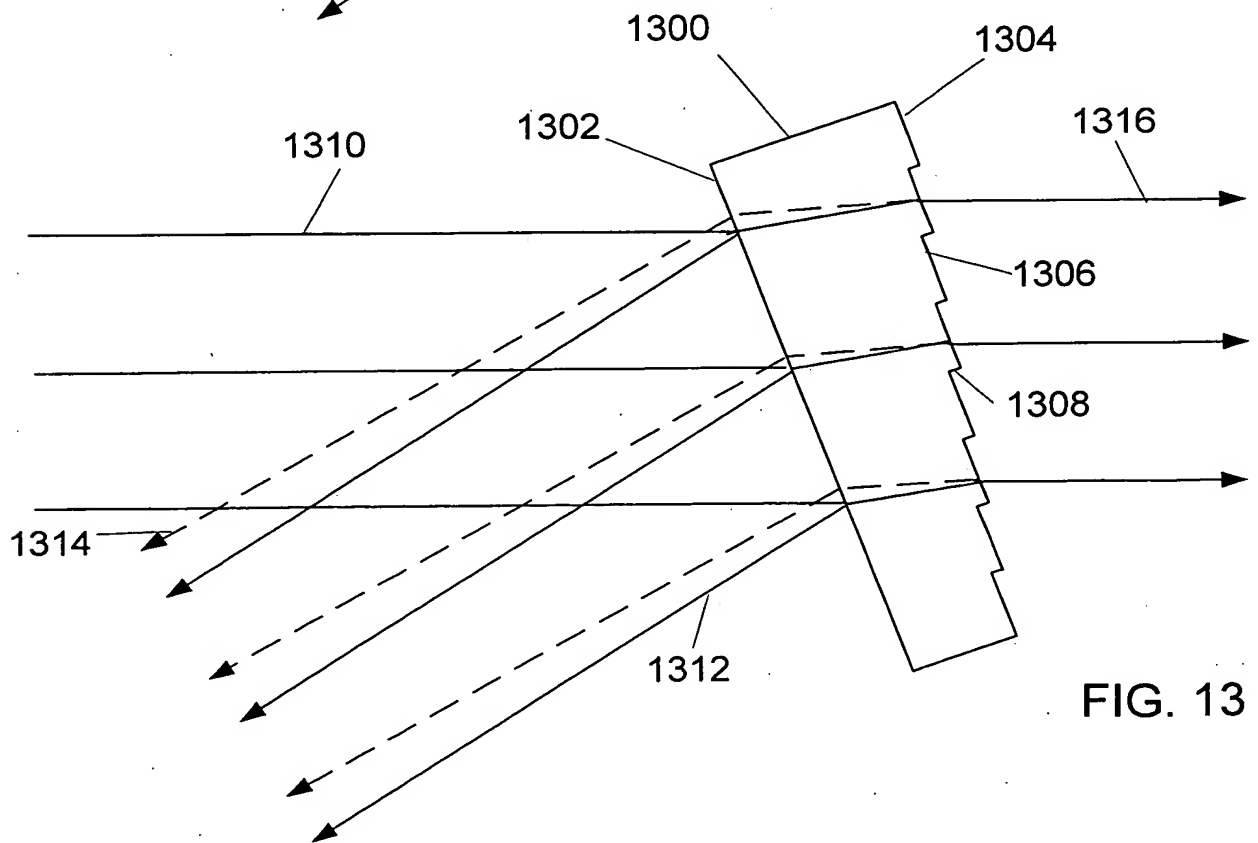


FIG. 13